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**RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2766**

PATENT
Attorney Docket No. 99154X204201

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Fang et al.

Application No. 09/595,227

Filed: June 16, 2000

For: METHOD FOR POLISHING A
MEMORY OR RIGID DISK WITH A
PHOSPHATE ION-CONTAINING
POLISHING SYSTEM

Art Unit: 2766

Examiner: Hadi Shakeri

pls.
H.S.
ENTER
a/s

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TECHNOLOGY CENTER R3700

RESPONSE TO OFFICE ACTION

Commissioner for Patents
Box AF
Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated June 13, 2002, please enter the following amendments and consider the following remarks.

AMENDMENTS

IN THE CLAIMS:

Please replace the indicated claims as follows:

1. (Amended) A method for planarizing or polishing a surface of a memory disk comprising abrading at least a portion of the surface with a polishing system comprising (i) a polishing composition comprising water, an oxidizing agent, and about 0.04 M or higher phosphate ion or phosphonate ion, and (ii) abrasive material.

4. (Amended) The method of claim 1, wherein the surface of the memory disk comprises nickel-phosphorus.